

|    | Hits | Search Text   | DBs   |
|----|------|---|---|
| 41 | 33   | ((system or apparatus or module) same (expos\$4 or irradiat\$4 or illuminat\$4) same (first or initial) same (alignment or interferometer)) and ((second or double or multiple or subsequent\$4 or sequent\$4) same (direct or maskless or blank\$2) same (expos\$4 or illuminat\$4 or irradiat\$4) same (apparatus or system or module)) and ((diffract\$4 or holographic or interference or (dual\$4 near6 beam)) same (expos\$4 or illuminat\$4 or pattern)) and (line\$3width or lines or (line near9 space)) and laser and (align\$6 same pattern same (post\$4exposure or post\$5develop\$4 or (second near5 (ilulminat\$4 or irradiat\$4 or expos\$4)))) | US-PGPUB;<br>USPAT; FPRS;<br>EPO; JPO;<br>DERWENT;<br>IBM_TDB |

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|----|----|---|--|
| 42 | 39 | <p>((system or apparatus or module) same (expos\$4 or irradiat\$4 or illuminat\$4) same (first or initial) same (alignment or interferometer)) and ((second or double or multiple or subsequent\$4 or sequent\$4) same (direct or maskless or blank\$2) same (expos\$4 or illuminat\$4 or irradiat\$4) same (apparatus or system or module)) and ((diffract\$4 or holographic or interference or (dual\$4 near6 beam)) same (expos\$4 or illuminat\$4 or pattern)) and laser and (align\$6 same pattern same (post\$4exposure or post\$5develop\$4 or (second near5 (iluminat\$4 or irradiat\$4 or expos\$4))))</p> | <p>US-PGPUB;<br/>USPAT; FPRS;<br/>EPO; JPO;<br/>DERWENT;<br/>IBM_TDB</p> |
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|    | Hits | Search Text   | DBs   |
|----|------|---|---|
| 43 | 48   | ((system or apparatus or module) same (expos\$4 or irradiat\$4 or illuminat\$4) same (first or initial) same (alignment or interferometer)) and ((second or double or multiple or subsequent\$4 or sequent\$4) same (direct or maskless or blank\$2) same (expos\$4 or illuminat\$4 or irradiat\$4) same (apparatus or system or module)) and ((diffract\$4 or holographic or interference or (dual\$4 near6 beam)) same (expos\$4 or illuminat\$4 or pattern)) and laser and (align\$6 same pattern same (post\$4exposure or post\$5develop\$4 or (second near5 (illuminat\$4 or irradiat\$4 or expos\$4)))) | US-PGPUB;<br>USPAT; FPRS;<br>EPO; JPO;<br>DERWENT;<br>IBM_TDB |